UNITED STATES PATENT AND TRADEMARK OFFICE

CONFIRMATION NO. 7102

Bib Data Sheet

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APPLICANTS

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** CONTINUING DATA *************************

This application is a REI of 09/614,764 07/12/2000 PAT 6,330,756 which is a DIV of 09/552,572 04/19/2000 PAT 6,301,801
which is a DIV of 09/461,432 12/16/1999 PAT 6,330,755
which is a CON of 09/177,495 10/23/1998 PAT 6,012,235
which is a CON of 09/061,062 04/16/1998 PAT 5,950,330
which is a CON of 08/882,731 06/26/1997 PAT 5,784,799
which is a DIV of 08/593,870 01/30/1996 PAT 5,661,913
which is a CON of 08/443,039 05/17/1995 PAT 5,553,396
which is a DIV of 08/302,443 09/09/1994 PAT 5,457,896
which is a CON of 08/096,256 07/26/1993 PAT 5,349,762
which is a CON of 07/751,951 08/29/1991 PAT 5,314,509

** FOREIGN APPLICATIONS *********************

JAPAN 02-225321 08/29/1990

IF REQUIRED, FOREIGN FILING LICENSE GRANTED
** 04/05/2002

Foreign Priority claimed ☒ yes ☐ no				
35 USC 119 (a-d) conditions met ☒ yes ☐ no ☐ Met after Allowance	STATE OR COUNTRY JAPAN	SHEETS DRAWING 2	TOTAL CLAIMS 9	INDEPENDENT CLAIMS 2
Verified and Acknowledged _Examiner's Signature_ _Initials_				

ADDRESS
20457

TITLE
VACUUM PROCESSING OPERATING METHOD WITH WAFERS, SUBSTRATES AND/OR SEMICONDUCTORS

FILING FEE RECEIVED 870	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:	☐ All Fees
		☐ 1.16 Fees (Filing)
		☐ 1.17 Fees (Processing Ext. of time)
		☐ 1.18 Fees (Issue)